Docket No.: 0834-0243-0



#12 6-21-02 Om

IN RE APPLICATION OF:

Hideaki SAKURAI, et al.

: EXAMINER: JACKSON

SERIAL NO: 09/457,743

Group I:

FILED: DECEMBER 10, 1999

: GROUP ART UNIT: 1773

FOR: PROTECTIVE THIN FILM FOR FPDS, METHOD FOR PRODUCING SAID THIN

FILM AND FPDS USING SAID THIN FILM

RESPONSE TO RESTRICTION REQUIREMENT

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

In response to the Office Action mailed April 9, 2002, the period for response having been extended to June 9, 2002, by a Petition for Extension of Time filed herewith, Applicants elect, with traverse, Group I, Claims 1, (3-6)/1, and 18/1 for further prosecution.

REMARKS

The Office has restricted this application as follows under 35 U.S.C. §121:

substrate, an oxide film body, and a fluoride layer;

Group II: Claims 2, (3-6)/2, and 18/2, drawn to a protecting film comprising a

substrate, an oxide film body, and a fluoride-coated powder layer;

Claims 1, (3-6)/1, and 18/1, drawn to a protecting film comprising a

Group III: Claims 7-10 and (12-13)/(7-9), drawn to a method of protecting film

by forming a fluoride layer from a gaseous substance in a vacuum;

Group IV: Claims 11 and (13-13)/11, drawn to a method of making a protecting

film utilizing a paste or dispersion;

Group V: Claims 16-17, drawn to a composition; and